

## § 469.10

by the application of the best practicable control technology currently available (BPT).

- 469.25 Effluent limitations representing the degree of effluent reduction attainable by the application of the best available technology economically achievable (BAT).
- 469.26 Pretreatment standards for existing sources (PSES).
- 469.27 New source performance standards (NSPS).
- 469.28 Pretreatment standards for new sources (PSNS).
- 469.29 Effluent limitations representing the degree of effluent reduction attainable by the application of the best conventional pollution control technology (BCT).

### Subpart C—Cathode Ray Tube Subcategory

- 469.30 Applicability.
- 469.31 Specialized definitions.
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### Subpart D—Luminescent Materials Subcategory

- 469.40 Applicability.
- 469.41 Specialized definitions.
- 469.42 New source performance standards (NSPS).
- 469.43 Pretreatment standards for new sources (PSNS).

AUTHORITY: Secs. 301, 304, 306, 307, 308, and 501 of the Clean Water Act (the Federal Water Pollution Control Act Amendments of 1972, as amended by the Clean Water Act of 1977, 33 U.S.C. 1311, 1314, 1316, 1317, 1318, and 1361; 86 Stat. 816, Pub. L. 92-500; 91 Stat. 1567, Pub. L. 95-217, unless otherwise noted.

SOURCE: 48 FR 15394, Apr. 8, 1983, unless otherwise noted.

### Subpart A—Semiconductor Subcategory

#### § 469.10 Applicability.

The provisions of this subpart are applicable to discharges resulting from all process operations associated with the manufacture of semiconductors, except sputtering, vapor deposition, and electroplating.

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#### § 469.11 Compliance dates.

The compliance deadline for the BAT fluoride limitation shall be as soon as possible as determined by the permit writer, but no later than November 8, 1985. The compliance deadline for the BAT and BCT limitations for total toxic organics (TTO) and pH, respectively, is as soon as possible as determined by the permit writer, but in no event later than July 1, 1984. The compliance date for PSES for TTO is July 1, 1984.

#### § 469.12 Specialized definitions.

The definitions in 40 CFR part 401 and the chemical analysis methods in 40 CFR part 136 apply to this subpart.

In addition,

(a) The term “total toxic organics (TTO)” means the sum of the concentrations for each of the following toxic organic compounds which is found in the discharge at a concentration greater than ten (10) micrograms per liter:

- 1,2,4 Trichlorobenzene chloroform
- 1,2 Dichlorobenzene
- 1,3 Dichlorobenzene
- 1,4 Dichlorobenzene ethylbenzene
- 1,1,1 Trichloroethane methylene chloride naphthalene
- 2 Nitrophenol phenol bis (2-ethylhexyl) phthalate tetrachloroethylene toluene trichloroethylene
- 2 Chlorophenol
- 2,4 Dichlorophenol
- 4 Nitrophenol pentachlorophenol di-n-butyl phthalate anthracene
- 1,2 Diphenylhydrazine isophorone butyl benzyl phthalate
- 1,1 Dichloroethylene
- 2,4,6 Trichlorophenol carbon tetrachloride
- 1,2 Dichloroethane
- 1,1,2 Trichloroethane dichlorobromomethane

(b) The term “semiconductors” means solid state electrical devices which perform functions such as information processing and display, power handling, and interconversion between light energy and electrical energy.

(c) The term “manufacture of semiconductors” means those processes, beginning with the use of crystal wafers, which lead to or are associated with the manufacture of semiconductor devices.

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